## INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)

	· · · · · · · · · · · · · · · · · · ·	
Docket Number (Optional)	Application Number	
TWI-5440	NEW	_
Applicant(s)		
David E. Aspnes et al.		
Filing Date	Group Art Unit	
HEREWITH	Unknown	

## U.S. PATENT DOCUMENTS

*Examiner Initial	REF	DOCUMENT NUMBER	DATE	Name	CLASS	SUBCLASS	FILING DATE

## FOREIGN PATENT DOCUMENTS

	DOCUMENT					TRANS	LATION
REF	Number	DATE	COUNTRY	CLASS	SUBCLASS	YES	No

## OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

0	A	(Including Author, Title, Date, Pertinent Pages, Esc.)
(7)	*BG	D.E. Aspnes, "Alignment of an Optically Active Biplate Compensator," Applied Optics, Vo. 10, pp. 2545-2546, November 1971.
71	*BH	D.E. Aspnes et al., "High Precision Scanning Ellipsometer," Applied Optics, Vol. 14, pp. 220-228, January 1975.
	*BI	D.E. Aspnes et al., "Photomultiplier Linearization and System Stablization for Photometric Ellipsometers and Polarimeters," SPIE, Vol. 112-Optical Polarimetry, pp. 62-66, 1977.
	*BJ	D.K. Burge et al., "Effect of a Thin Surface Film on the Ellipsometric Determination of Optical Constants," Journal of the Optical Society of America, Vol. 54, No. 12, pp. 1428-1433, December 1964.
	*BK	B.D. Cahan, "Implications of Three Parameter Solutions to the Three-Layer Model," Surface Science, Vol. 56, pp. 354-372, 1976.
	*BL	D. Clarke et al., "Polarized Light and Optical Measurment,," Chapter 4 and bibliography, Pergamon Press Ltd., Oxford, pp. 118-154 and 179-182, 1971.
	*BM	D. Clarke et al., "A Three-Channel Astronomical Photoelectric Spectropolarimeter," Journal of Scientific Instruments (Journal of Physics E), Series 2, Vol. 1, pp. 409-412, 1968.
	*BN	W. Duncan et al., "Insitu Spectral Ellipsometry for Real-Time Measurement and Control," Applied Surface Science, Vol. 63, pp. 9-16, 1993.
	*BO	T. Gehrels (ed.), "Planets, Stars and Nebulae Studied with Photopolarimetry," University of Arizona Press, pp. 135-175, 1974.
·	*BP	A. Hamnett et al., "A Ellipsometric Study of Polypyrrole Films on Platinum," J. Electroanal Chem., Vol. 270, pp. 479-488, 1989.
	*BQ	P.S. Hauge, "Generalized Rotating-Compensator Ellipsometry," Surface Science, Vol. 56, pp. 148-160, 1976.
	*BR	P.S. Hague, "Recent Developments in Instrumentation in Ellipsometry," Surface Science, Vol. 96, pp. 108-140, 1980.
	*BS	P.S. Hague, "A Rotating-Compensator Fourier Ellipsometer," Engineering Technology, 5 pages in length, March 1975.
	*BT	E.B. Hodgdon, "Theory, Design, and Calibration of a UV Spectrophotopolarimeter," Applied Optics, Vol. 4, No. 11, pp. 1479-1483, November 1965.
	*BU	Y.T. Kim et al., "Fast Scanning Spectroelectrochemical Ellipsometry: In-Situ Characterization of Gold Oxide," Surface Science, Vo. 233, pp. 341-350, 1990.
	*BV	H.V. Nguyen et al., "Evolution of the Optical Functions of Thin-Film Aluminum: A Real-Time Spectroscopic Ellispometry Study," American Physical Society. Physical Review B, Vol. 47, No. 7, pp. 3947-3965, February 1993.
	*BW	W. Paik et al., "Exact Ellipsometric Measurement of Thickness and Optical Properties of a Thin Light-Absorbing Film Without Auxiliary Measurements," Surface Science, Vol. 28, pp. 61-68, 1971.
	*BX	Z. Sekera, "Recent Developments in the Study of the Polarization of Sky Light," Advances in Geophysics, Vol. 3, pp. 43-104, 1956.
	*BY	D.E. Aspnes et al., "Rotating-Compensator/Analyzer Fixed-Analyzer Ellipsometer: Analysis and Comparison to Other Automatic Ellipsometers," J. Opt. Soc. Am., Vol. 66, No. 9, Sept. 1976, pp. 949-954.
2	*BZ	J.H.W.G. Den Boer et al., "Spectroscopic Rotating Compensator Ellipsometry in the Infrared: Retarder Design and Measurement," Meas. Sci. Technol., Vol. 8, January 20, 1997, pp. 484-492.
	<del></del>	

Estaminer for face	Date Considered 8/7-04				
Examiner: Initial il citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.					
not in couplinance and not considered. Include copy of this lot in with dext combunication to applicant.					

Modified Form PTO-A820 (also form PTO-1449)

Sheet 2 of 2